



#4/A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	)	Examiner: Unknown
	)	
FISCHER et al.	)	
	)	Art Unit: 2817
Application No. 10/077,072	)	
	)	Docket No. P0877
Filed: February 14, 2002	)	
	)	Date: April 8, 2002
For: A Plasma Processing Apparatus	)	
And Method for Confining An RF Plasma	)	
Under Very High Gas Flow and RF Power	)	
Density Conditions (As Amended)	)	
	)	
	)	

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on April 8, 2002.

Signed:

Sharon D. Tillery  
Sharon D. Tillery

Preliminary Amendment

Commissioner for Patents  
**Box Non-Fee Amendment**  
Washington, DC 20231

✓ Sir:

Please enter the following preliminary amendment prior to examining the above referenced patent application.

IN THE TITLE

Please change the title from "A Plasma Processing Apparatus and Method" to  
--A Plasma Processing Apparatus and Method for Confining an RF Plasma Under  
Very High Gas Flow and RF Power Density Conditions--